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### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 3753

162 N. Wolfe Road Sunnyvale, CA 94086

Customer No.: 28960

(408) 530-9700

TRANSMITTAL LETTER

Examiner:

In re Application of:	
Douglas Werner et al.	
Serial No.: 10/769,717	
Filed: January 29, 2004	

For:

HERMETIC CLOSED LOOP

**FLUID SYSTEM** 

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313

Sir:

Enclosed please find an Information Disclosure Statement and Form PTO-1449, including copies of the references contained thereon, for filing in the U.S. Patent and Trademark Office.

You will also find enclosed the associated Transmittals, Electronic Information Disclosure Statements, and United States Patent and Trademark Office Acknowledgment Receipts for the electronically filed Information Disclosure Statement (EFS ID #200407141632055371570343502050701044); (EFS ID #64520); and (EFS ID #64521) filed on July 14, 2004.

The Commissioner is hereby authorized to charge any additional fee or credit overpayment to our Deposit Account No. <u>08-1275</u>. An originally executed duplicate of this transmittal is enclosed for this purpose.

Respectfully submitted,

HAVERSTOCK & OWENS LLP

Dated: 7-14-04

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Attorneys for Applicants

CERTIFICATE OF MAILING (37 CFR§ 1.8(a))

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450

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Date: 7/15/04 By



#### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	) Group Art Unit: 3753
Douglas Werner et al.	Examiner:
Serial No.: 10/769,717	) <u>INFORMATION DISCLOSURE</u> ) <u>STATEMENT</u>
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Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313

Sir:

The citations listed below, copies attached, may be material to the examination of the above-identified application, and are therefore submitted in compliance with the duty of disclosure defined in 37 C.F.R. §§ 1.56 and 1.97. The Examiner is requested to make these citations of official record in this application.

United States Patents or Published Patent Applications have been filed electronically (EFS ID #200407141632055371570343502050701044); (EFS ID #64520); and (EFS ID #64521). Applicants have become aware of the following printed publication which may be material to the examination of this application:

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This Information Disclosure Statement under 37 C.F.R. §§ 1.56 and 1.97 is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that anyone or more of these citations constitutes prior art.

Respectfully submitted,

HAVERSTOCK & OWENS LLP

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` ′	ON DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary)	Applicants: Douglas Werner et al.	T-1-
(37 CFR § 1.98(b))	(Use Several Sheets if Necessary)	Filing Date: January 29, 2004	Group Art Unit: 3753
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` '	RMATIO	ON DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary)	Applicants: Douglas Werner et al.	
(37 CFR § 1.98(b		(Use Several Sheets if Necessary)	Filing Date: January 29, 2004	Group Art Unit: 3753
		OTHER DOCUMENTS (Including Author, Title, D	ate, Relevant Pages, Place of Publication)	
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# UNITED STATES PATENT AND TRADEMARK OFFICE ACKNOWLEDGEMENT RECEIPT

Electronic Version 1.1 Stylesheet Version v1.1.1

Title of Invention			
Submission Type:			
Application Number:			
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HERMETIC CLOSED LOOP FLUID SYSTEM Invention Title of

\*10/769717\* 10/769717 Application Number:

2004-01-29

Date:

Douglas Werner First Named Applicant:

8804 Confirmation Number:

Attorney Docket Number:

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Thomas B. Haverstock	/tbh/	
Registered Number: 32571		Attorney

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#### **ELECTRONIC INFORMATION DISCLOSURE STATEMENT**

Electronic Version v18 Stylesheet Version v18.0

Title of HERMETIC CLOSED LOOP FLUID SYSTEM

Invention

10/769717

Application Number: Confirmation Number: 8804 First Named Applicant: Douglas Werner

Attorney Docket Number:

Search string:

( 3654988 or 3817321 or 3823572 or 3923426 or 3929154 or 4109707 or 4194559 or 4248295 or 4485429 or 4561040 or 4664181 or 4866570 or 4894709 or 4896719 or 4908112 or 5009760 or 5058627 or 5070040 or 5088005 or 5096388 or 5099311 or 5099910 or 5125451 or 5131233 or 5203401 or 5218515 or 5219278 or 5232047 or 5239200 or 5263251 or 5274920 or 5309319 or 5317805 or 5325265 or 5336062 or 5380956 or 5383340 or 5427174 or 5436793 or 5514906 or 5544696 or 5548605 or 5579828 or 5585069 or 5641400 or 5692558 or \$696405 or 5703536 or 5704416 or 5727618 ).pn.

**US Patent Documents** 

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Examiner Name	Date

# UNITED STATES PATENT AND TRADEMARK OFFICE ACKNOWLEDGEMENT RECEIPT

Electronic Version 1.1 Stylesheet Version v1.1.1

HERMETIC CLOSED LOOP FLUID SYSTEM Title of Invention Information Disclosure Statement Submission Type: \*10/769717\* 10/769717 Application Number: 64521 EFS ID: Server Response: Confirmation Message Code Submission was successfully submitted - Even if Informational or Warning Messages appear ISVR1 below, please do not resubmit this application ICON1 8804 For assistance with e-filing a patent application, contact the Patent Electronic Business Center: USPTOEFSNotice Toll-Free Number:1(866) 217-9197 Website: http://www.uspto.gov/ebc/ First Named Applicant: Douglas Werner Attorney Docket Number: Timestamp: 2004-07-14 13:14:25 EDT From: us File Listing: Doc. Name File Name Size (Bytes)

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\*10/769717\* 10/769717 Application Number:

2004-01-29 Date: Douglas Werner First Named Applicant:

Confirmation Number: 8804

Attorney Docket Number:

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Registered Number: 32571		Attorney

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### ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v1 8
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Invention

tylesheet Version v1 8.0

HERMETIC CLOSED LOOP FLUID SYSTEM

Application Number: 10/769717

10/750717

Confirmation Number: 8804
First Named Applicant: Douglas Werner

Attorney Docket Number: Search string: (

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init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
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$\neg$	2	6317326	2001-11-13	Vogel et al.	B1		
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	5	6324058	2001-11-27	Hsiao	BI		
	6	6351384	2002-02-26	Daikoku et al.	Bi		
	7	6337794	2002-01-08	Agonafer et al.	B1		
$\neg$	8	6388317	2002-05-14	Reese	B1		
ヿ	9	6400012	2002-06-04	Miller et al.	B1		
	10	6406605	2002-06-18	Moles	B1		

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11         6415860         2002-07-09         Kelly et al.         B1           12         6416642         2002-07-09         Alajoki et al.         B1           13         6417060         2002-07-09         Tavkhelidze et al.         B1           14         6424531         2002-07-23         Bhattl et al.         B1           15         6443222         2002-09-03         Yun et al.         B1           16         6444461         2002-09-03         Knapp et al.         B1           17         6457515         2002-10-01         Vafai et al.         B1           18         6495015         2002-12-17         Schoeniger et al.         B1           19         6537437         2003-02-25         Galambos et al.         B1           20         6543521         2003-04-08         Sato et al.         B1           21         6553253         2003-04-02         Chang         B1           22         6572749         2003-06-03         Paul et al.         B1           23         6588498         2003-07-08         Reysin et al.         B1           24         6591625         2003-07-15         Simon         B1           25         6632655						
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14	12	6416642	2002-07-09	Alajoki et al.	BI	
15	13	6417060	2002-07-09	Tavkhelidze et al.	BI	
16 644461 2002-09-03 Knapp et al. B1 17 6457515 2002-10-01 Vafai et al. B1 18 6495015 2002-12-17 Schoeniger et al. B1 19 6537437 2003-03-25 Galambos et al. B1 20 6543521 2003-04-08 Sato et al. B1 21 6553253 2003-04-02 Chang B1 22 6572749 2003-06-03 Paul et al. B1 23 6588498 2003-07-08 Reysin et al. B1 24 6591625 2003-07-15 Simon B1	14	6424531	2002-07-23	Bhattl et al.	В1	
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24 033(02) 2533 0, 13	23	6588498	2003-07-08	Reysin et al.	BI	
25 6632655 2003-10-14 Mehta et al. B1	24	6591625	2003-07-15	Simon	B1	
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init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20010016985	2001-08-30	Insley et al.	Αl		79
	2	20010024820	2001-09-27	Mastromatteo et al.	Al		
	3	20010044155	2001-11-22	Paul et al.	Al		
	4	20010045270	2001-11-29	Bhatti et al.	A1		
	5	20010046703	2001-11-29	Burns et al.	Αl		
	6	20010055714	2001-12-27	Cettour-Rose et al.	Al		
	7	20020011330	2002-01-31	Insley et al.	Al		

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